L Number	Hits	S arch Text	DB	Time stamp
1	751	(((Core and clad\$4) ) and wave\$guide and	USPAT;	2003/02/12
		(mask or hard4mask r etch\$ mask)) and	US-PGPUB;	08:53
		(resist r ph t resist)	DERWENT	
3	164	((((Core and clad\$4) ) and wave\$guide and	USPAT;	2003/02/12
		(mask or hard4mask or etch\$ mask)) and	US-PGPUB;	11:08
		(resist or photoresist)) and (Cr or chrome or	DERWENT	
_	451	chromium) ((((Core and clad\$4) ) and wave\$guide and	USPAT:	2003/02/12
5	451			10:35
		(mask or hard4mask or etch\$ mask)) and	US-PGPUB;	10:35
		(resist or photoresist)) and \$4align\$4	DERWENT	0000/00/40
7	97	(((((Core and clad\$4) ) and wave\$guide and	USPAT;	2003/02/12
		(mask or hard4mask or etch\$ mask)) and	US-PGPUB;	11:09
		(resist or photoresist)) and (Cr or chrome or	DERWENT	
		chromium)) and (align\$3 or self\$align\$3)		
8	95	((((((Core and clad\$4) ) and wave\$guide and	USPAT;	2003/02/12
		(mask or hard4mask or etch\$ mask)) and	US-PGPUB;	11:10
		(resist or photoresist)) and (Cr or chrome or	DERWENT	
	0 25 - 15	chromium)) and (align\$3-or self\$align\$3)) and		
		(quartz or silica or SiO2 or Glass)		
-	989	(430/321).CCLS.	USPAT;	2003/02/10
			US-PGPUB;	11:31
			DERWENT	
-	143	(216/25,26).CCLS.	USPAT;	2003/02/10
			US-PGPUB;	15:12
			DERWENT	
_	882	Wave\$guide and micro\$machin\$4	USPAT;	2003/02/10
			US-PGPUB;	15:30
			DERWENT	
_	580	(Wave\$guide and micro\$machin\$4) and	USPAT;	2003/02/10
		etch\$4	US-PGPUB;	15:15
		3.0.0	DERWENT	10110
_	35	(Wave\$guide and micro\$machin\$4).clm.	USPAT;	2003/02/10
	33	(waveyguide and inicioyinacinii)4-).ciiii.	l	
			US-PGPUB; DERWENT	16:52
_	49	(Wave\$guide and micro\$machin\$4) and		2003/02/10
-	49		USPAT;	
		self\$align\$3	US-PGPUB;	15:30
	215		DERWENT	0000100140
-	218	(Wave\$guide and micro\$machin\$4) and	USPAT;	2003/02/10
		((Core and clad\$4) )	US-PGPUB;	16:43
	. = =	(	DERWENT	
-	125	(65/385).CCLS.	USPAT;	2003/02/10
			US-PGPUB;	16:50
			DERWENT	
•	101	(65/429).CCLS.	USPAT;	2003/02/10
			US-PGPUB;	17:40
			DERWENT	
	1095	(385/88).CCLS.	USPAT;	2003/02/10
			US-PGPUB;	16:52
			DERWENT	
	19	(Wav \$guide and micr \$machin\$4) and	USPAT;	2003/02/10
		((385/88).CCLS.)	US-PGPUB;	16:59
			DERWENT	

-	754	(385/129).CCLS.	USPAT;	2003/02/10	-
		•	US-PGPUB;	16:59	
			DERWENT		
-	19	(Wave\$guid and micr \$machin\$4) and	USPAT;	2003/02/10	
		((385/129).CCLS.)	US-PGPUB;	17:02	
			DERWENT		
-	926	(385/147).CCLS.	USPAT;	2003/02/10	
			US-PGPUB;	17:02	
			DERWENT		
-	4	(Wave\$guide and micro\$machin\$4) and	USPAT;	2003/02/10	
		((385/147).CCLS.)	US-PGPUB;	17:02	
			DERWENT		
-	250	((Core and clad\$4) ) and ((385/88).CCLS.)	USPAT;	2003/02/10	
			US-PGPUB;	17:41	
			DERWENT		
•	27947	(Core and clad\$4)	USPAT;	2003/02/11	
			US-PGPUB;	18:06	
			DERWENT		
•	67672	wave\$guide	USPAT;	2003/02/11	
	_0		_US-PGPUB;=	-18:07	
en (am en)			DERWENT		
•	464166	mask or hard4mask or etch\$ mask	USPAT;	2003/02/11	
			US-PGPUB;	18:08	
			DERWENT		
-	3007	((Core and clad\$4) ) and wave\$guide and	USPAT;	2003/02/11	
		(mask or hard4mask or etch\$ mask)	US-PGPUB;	18:09	
		•	DERWENT		
	310275	resist or photoresist	USPAT;	2003/02/11	
			US-PGPUB;	18:10	
			DERWENT		